

## MEMS 2003 Report

MEMS2003, The 16<sup>th</sup> Annual International IEEE Micro Electro Mechanical Systems Conference, was held from January 19 to 23, 2003, at the Kyoto International Conference Hall, Japan.

The 500 pre-publication papers submitted for presentation at MEMS2003 exceeded last year's record of 454, and of these, 22 were chosen for oral and 151 for poster presentations, a selection rate of approximately 35%. Since applications mushroomed in 1995, it has become increasingly difficult to have a paper accepted for presentation at a MEMS conference. Although attendance at this year's conference was 664, slightly less than the 700 who attended MEMS2002 in Las Vegas, USA, last year, the fact that approximately half the participants were from overseas ensured that the conference was, as its name promises, a truly international event.

MEMS began in 1987 as the Micro Robots and Teleoperators Workshop, and the present name was adopted in 1999. Although the number of presentation papers and conference participants has gradually increased over the years, MEMS has consistently maintained its original single session format for oral presentations. The number of oral presentations at MEMS2003 was reduced from the previous year's 41 to 22, partly in order to ensure a consistent selection rate. Needless to say, this decision was neither an easy for organizers to make, nor necessarily welcomed by participants. However, in the poster sessions, for which a much greater number of presentations were accepted, the standard of research in a large proportion of presentations was very high. Furthermore, in Poster Preview sessions, a new feature introduced experimentally at MEMS2003, held prior to the poster sessions each day, the content of presentations was classified into relevant categories and topics selected by commentators explained, and this additional service was well-received among participants.

By region, the largest number of poster presentations was made by American researchers (71 presentations), followed by Japanese researchers (49 presentations). Although the number of presentations by European researchers was noticeably small (19 presentations) this year, the number of presentations by Korean and Taiwanese researchers again rose over the previous year.

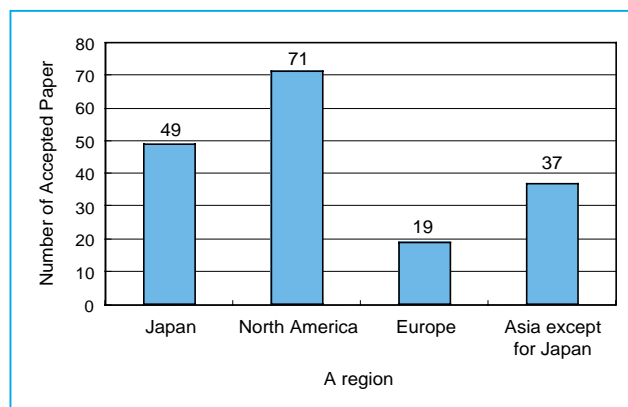
According to the results of a questionnaire answered by conference attendees, participants showed the greatest interest in presentations

concerning either materials or processing technologies, but interest in bio- and micro fluid-related topics combined was greatest overall. The strong interest in these two fields is a growing trend that has been commonly observed in micromachine-related international conferences of late.

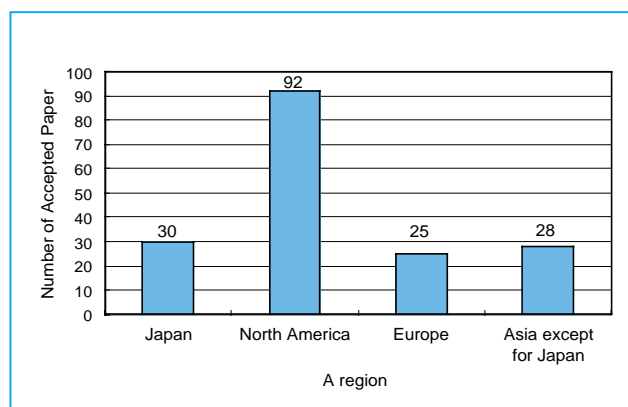
Breakdowns of the papers submitted to and presented at MEMS2003 according to topic and region, as well as the results of the attendees' questionnaire, are available on the Ritsumeikan University website (<http://www.ritsumei.ac.jp/se/~tabata/mems2003/>).

The MEMS2003 Proceedings (soft cover/ 711 pages/ 12,000 per copy (¥10,000 for IEEE members), CD-R and shipping fee included) can be ordered from the following website: <http://home.inter.net/mems2003/>

The 17<sup>th</sup> Annual International IEEE Micro Electro Mechanical Systems Conference, MEMS2004, is to be held in Maastricht, The Netherlands, from January 25 to 29, 2004. Program details are available from the following website: <http://www.mems2004.org>



**Fig. 1 Regional Distribution of accepted Paper for MEMS2003**



**Fig. 2 Regional Distribution of accepted Paper for MEMS2002(For Reference)**